The influence of the Ne/Ar buffer gases on the XeI₂ excimer radiation intensity in a dielectric barrier discharge at moderate pressures

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The paper presents the comparative results concerning the excimer intensity radiation emitted by a xenon-iodine gas mixture with and without buffer-gases, namely Ar and Ne, in a dielectric barrier discharge (DBD) at moderate pressure. The excimer radiation reaches an optimum for a given value of the gas mixture total pressure due to the existence of two antagonist processes: the "harpoon" reaction and the quenching reaction. Changes appear in the presence of the buffer-gas. Thus, the addition of the Ar to the XeI- excimer gas mixture diminishes the excimer radiation intensity while the Ne addition produces an enhancement of the emitted radiation.

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1. Introduction

Excimers represent a class a molecules formed by the combination between a halogen and a rare gas. These molecules do not exist in the ground state which is unstable but only in an excited state. By a dissociating deexcitation process it can be generated UV excimer radiation which is a quasi-monochrome radiation. A molecular band is emitted at the transition from the upper excited molecular state to the lower level of the non-excited unstable molecule. The study was performed in a dielectric barrier discharge (DBD) having a plasmagen gas mixture formed by the rare gas-xenon (R_g), the halogen (X)-iodine and the *buffer gases* – neon /argon.

The formation of the excimer molecules starts with the excitation and ionization of the xenon atoms and molecular iodine by high energy electrons collisions produced in glow-DBD phase [1-7]:

$$e + Xe \rightarrow 2e + Xe^{+} \tag{1}$$

$$\rightarrow e + Xe^*$$
 (2)

$$e + I_2 \rightarrow 2e + I + I^+ \tag{3}$$

$$\rightarrow 2e + I_2^+ \tag{4}$$

$$\rightarrow I + I^-$$
 (5)

$$\rightarrow e + I_2^*$$
 (6)

At low pressure (0.5-5) Torr the major reaction for the excimer formation seems to be the *reverse Harpoon* –

reaction between ground state xenon and excited states (³P, ¹D) of molecular iodine:

$$Xe + I_2 \xrightarrow{*} XeI^*(B) + I$$
 (7)

This reaction is a two-body reaction and for this reason is attractive for the formation of excimer molecules at low pressure.

At high pressure (10-760 Torr) the XeI^{*} molecules excimer are generated either by the *Harpoon- reaction* or the three-body ionic recombination, depending on the range pressure of work.

Thus, at 10s Torr pressure the major reaction for excimer formation is the *Harpoon reaction*. The excited states of the xenon atoms are transferring an electron to the iodine molecule (or compounds containing iodine) and form electronically excited states of the excimer molecules:

$$Xe^* + I_2 \rightarrow XeI^*(B) + I$$
 (8)

At 100s Torr pressure the major reaction for excimer formation is the ionic recombination:

$$Xe^+ + I^- + M \rightarrow XeI^*(B) + M$$
 (9)

There are still other indirect reactions involved in the generation of the excimer molecules like the following:

$$Xe^* + I + M \rightarrow XeI^* + M$$
 (10)

$$Xe_{2}^{+}+I \rightarrow XeI^{*}+Xe$$
 (11)

$$Xe_2^* + I_2 \rightarrow XeI^* + Xe + I$$
 (12)

The electronically excited excimer molecules XeI(B) decay radiatively to the molecular ground state in connection with the rapid excimer molecule dissociation attributed to bound-free transitions:

$$XeI^* \to Xe+I + hv (253/265/320 nm)$$
 (13)

The mechanisms of excimer generation compete with the quenching mechanisms:

$$Xe^{+} + Xe + M \rightarrow Xe_{2}^{+} + M$$
 (14)

$$Xe^{+} + I_2 \rightarrow Xe + I_2^{+}$$
(15)

$$Xe^* + Xe + M \rightarrow Xe_2^* + M$$
(16)

$$Xe^* + I_2 \longrightarrow Xe + I_2^+ + e \tag{17}$$

$$Xe^* + I \rightarrow Xe + I^+ + e$$
 (18)

$$I_2^+ + e + M \rightarrow I_2^* + M$$
 (19)

 $XeI^* + Xe \rightarrow 2Xe + I$ (20)

$$XeI^* + 2Xe \rightarrow Xe_2I^* + Xe$$
 (21)

$$\operatorname{XeI}^{*} + \operatorname{Xe} + \operatorname{I}_{2} \to \operatorname{Xe}_{2}\operatorname{I}^{*} + \operatorname{I}_{2}$$
(22)

$$XeI^* + I_2 \rightarrow Xe + I_2^* + I$$
 (23)

As it can be observed from the reactions (14) and (16) the direct precursors of the excimer, namely Xe^+ and Xe^* , are consumed but in exchange appear far- precursors of the excimer, namely Xe_2^+ and Xe_2^+ .



Fig. 1. Potential energy diagram of Xel^{*} excimer molecule.

The ionizing Penning reactions (17) and (18), become very important at high partial pressure of iodine, consuming lots of Xe^{*}, one of the most important precursor of XeI^{*} excimer. In the same time, the molecular iodine produces an increase of the iodine dimer radiation and quenches the excimer XeI^{*}- reaction (23).

From the reactions (21) and (22) it can be observed the formation of the trimer Xe_2I^* process which is increasing with the high pressures.

A diagram of the potential energy for the xenoniodine excimer molecule is given in the Fig. 1. The ground-state $X_{1/2}$ is formed from the ground-state ¹S of the noble gas atom and the ²P (s=1/2, l=1, m_l=0) energetic level of the halogen atom. The $A^{-2}P_{1/2,3/2}$ state derives from the ground-state ¹S of the noble gas atom and the ²P (s=1/2, l=1, m_l=±1) energetic level of the halogen atom. The three excited levels $-B_{1/2}$, $C_{3/2}$ si $D_{1/2}$ – derive from the ²P pozitive noble gas ion and ¹SX⁻ negative halogen ion.

The transitions $D_{1/2}/B_{1/2} \rightarrow X_{1/2}$ and $C_{1/2}/B_{1/2} \rightarrow A_{1/2}$ inclusive the wavelenghts values associated for the principal excimers are presented in the Table 1.

Table 1.

		R_gX^*	R_gX^*	R_gX^*	R_gX^*	
Rg	Х	$D_{1/2} \rightarrow X_{1/2}$	$B_{1/2} \rightarrow$	$C_{1/2} \rightarrow A_{1/2}$	$B_{1/2} \rightarrow$	Rg_2X^*
Ū.		(nm)	X _{1/2}	(nm)	A _{1/2}	(nm)
			(nm)		(nm)	
Ne	F	106	108	110	111	±145
Ar	F	185	193	203	204	290±25
Ar	Cl	-	175	-	195	245±15
Ar	Br	-	165	172	183	-
Kr	F	220	248	275	272	400±35
Kr	Cl	200	222	240	235	325±15
Kr	Br	-	207	222	228	~318
Kr	Ι	-	190	195	225	-
Xe	F	264	351	460	410	610±65
Xe	Cl	236	308	345	340	450±40
Xe	Br	221	22	300	325	440±30
Xe	Ι	203	253	265	320	~375

As the transitions are of molecular type, λ is corresponding to the peak-value of the spectral emission band. The intensity of the emitted radiation and the halfwidth of the spectral lines emitted in different transitions are very different. For instance, the $D_{1/2} \rightarrow X_{1/2}$ transition generates the shorter wavelenght while his intensity is much weaker than for the $B_{1/2} \rightarrow X_{1/2}$ transition, fact which indicates that the population of the upper energetic level $D_{1/2}$ is diminished by non-radiative processes. The $B_{1/2} \rightarrow X_{1/2}$ transition is the strongest of all because the electronic orbitals *sp* have the largest overlap from the valence orbitals.

Typical emission of Xel^{*} excimer provides an intense narrow-band radiation at λ = 253 nm within dielectric barrier discharge. This spectral line proceeds from the transition B_{1/2} \rightarrow X_{1/2}. In the diagram, X_{1/2} represents the ground state and the B_{1/2} the first vibrational excited state of the rare gas/halogen molecule excimer. Other spectral lines that could appear in the discharge are λ =206nm and λ =342nm from the atomic respectively molecular iodine and the excimeric spectral lines λ =265nm, 320nm and 375nm, suitable to the transitions between vibrational excited states $C \rightarrow A$, $B \rightarrow A$ and respectively the Xe_2I^* trimer spectral line (Table 1).



Fig.2. Geometry of cylindrical excimer UV discharge

2. Experimental set-up

A classic cylindrical coaxial lamps configuration was used in our experiments. The UV radiation generated was radiating outward the discharge device.

The lamp is composed of two concentric quartz tubes, outer and inner metallic electrodes, both made by steel, an external RF high voltage generator (up to 20kV), and a heating system of the iodine pure crystals. The discharges were matching at a sinusoidal voltage value of about 4kV with the frequency range between 20–400 kHz. The high voltage was applied on the inner electrode, while the outer UV mesh transparent electrode was grounded. The experimental set-up was presented in detail in our previous paper ^[8]. In order to record the emission spectra an OMA (Optical Multichannel Analyzer), spectral range between 200-900 nm, and 1.5nm resolution, was used. The integration time was in the range of 0.5-1 ms.

3. Results and discussion

It was measured the dependence of the spectral excimer intensities on the percentages of *buffer gases*, in order to establish the influence of their addition at the emitted radiation intensity of the xenon – iodine primary mixture.

The spectral intensities that appear in the graphs are relative being given in arbitrary units. The total pressure of the gas mixtures varied in the range of 20-45 Torr. High purity (99.998%) rare gases–Xenon, Iodine, Argon and Neon were used in the experiments.

As it can be observed from the Fig. 3, the intensity of the excimer radiation with $\lambda = 253$ nm in the presence of argon as *buffer-gas* is lower than that which is obtained without using buffer gas, at the same value of the total gas pressure, which is 35 Torr. In the same time, the intensity of the trimer Xe₂I^{*} is higher in the presence of *buffer gas* than in his absence. This behavior can be explained taking

into account the possibility that the molecules of argon displace xenon in reactions (14) and (16) by quenching the precursors Xe⁺ and Xe^{*} or in reaction (20) by quenching the excimer Xel^{*}, which leads to the decreasing of the excimer radiation. This behavior of argon could be produced by the fact that Ar spectrum of the excited energetic levels in Paschen notation is formed by 4 s- lines ($1s_2$ - $1s_5$) and 10 p- lines ($2p_1$ - $2p_{10}$), which increase the possibility of collisional couplings with the xenon atoms levels, followed by non-radiative dezexcitation. From the reactions (21) and (22) results that the intensity of Xe₂I^{*} trimer spectral band centered at λ =375nm can increase for the same reason.



Fig. 3. Emission spectrum of XeI respectively (Xe+I+Ar) gas mixtures in a DB discharge.



Fig. 4. The dependence excimer intensity for $\lambda = 253$ nm on the argon percentage for (Xe+I+Ar) gas mixtures in a DB discharge.

From the Fig. 4 results that the intensity of the main excimer spectral line λ =253nm reaches an optimum at a percentage of 62.85% argon, respectively 11.42% iodine. As in the case of the (Xe+I₂) gas mixture after a given value of the iodine partial pressure, the intensity of the 253nm spectral line diminishes due to the formation of the iodine I₂⁺ dimer based on the three-body reactions (19), (23).



Fig. 5. Emission spectrum of XeI respectively (Xe+I+Ne) gas mixturesin a DB discharge

In the Fig. 5 is presented the emission spectrum of $(Xe+I_2)$ gas mixture with the iodine pressure of 5 Torr, and the emission spectra of $(Xe+I_2+Ne)$ gas mixture with the iodine pressure of 5 Torr, respectively 10 Torr. As it can be observed, the main excimer line intensity λ =253nm is higher in the presence of Ne *buffer gas* (graph B) than in his absence (graph C). This behavior could be attributed to the fact that neon atoms could stand for the third body in the reactions (9) and (10).

The excimer radiation intensity emitted by a (Xe+I+Ne) gas mixture at a total pressure of 35 Torr and an iodine partial pressure of 10 torr is lower than the excimer intensity emitted in the same experimental conditions but with a partial iodine pressure of 5 Torr. According to the reported literature data ^[5], increasing the iodine partial pressure, the Penning reactions (17) and (18) and the reaction (23) are destroying many Xe^{*}(B) excimer molecules, decreasing in this way the emitted excimer radiation (graph D).



Fig. 6 The dependence excimer intensity for λ =253nm on the neon percentage for (Xe+I+Ne) gas mixtures in a DB discharge.

The excimer intensity reaches an optimum for a neon percentage value of 42.85% (at a partial pressure iodine of 5 Torr) respectively 34.28% (at a partial pressure iodine of 10 Torr). It can be observed that the relative intensity of the 253 nm spectral line is lower at high concentration of iodine. The total gas mixture pressure was kept at 35 Torr value –Fig. 6.



Fig. 7. Emission spectrum of (Xe+42.85%Ne+I) gas mixture in a DB discharge at at $p_{tot}=35$ Torr

In Fig. 7 is presented the dependence of the excimer intensity for (Xe+42.85%Ne+I) gas mixture at a total pressure of 35 Torr. It can be observed that the excimer spectral line λ =320nm and the molecular iodine spectral line λ =342 nm are very intensive.

4. Conclusions

The addition of a buffer gas to the primary xenoniodine mixture produces, according to the circumstances, an increasing of the 253 nm main excimer spectral line, like in the case of the neon addition or a decreasing, like in the case of argon addition. Other spectral lines emitted by the main excimer or iodine dimer are influenced too in the process of the buffer gases addition.

The mechanisms on which is based this emission of the excimer radiation emitted by the xenon-iodine gas mixture seem to be quiet different comparing with the case of other excimers like KrCl^{*} or XeCl^{*}, in the sense that the optimum excimer intensity is reached for much lower iodine percentages than for chlorine.

It was be necessary a future study of the XeI^{*} mechanisms formation in order to optimize the device of the excimer lamps based on the xenon-iodine mixture.

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